

INFORMATION DISCLOSURE STATEMENT

Applicant	:	Taku Hirayama
App. No	:	10/590,046
Filed	:	June 15, 2007
For	:	BASE MATERIAL FOR PATTERN-FORMING MATERIAL, POSITIVE RESIST COMPOSITION AND METHOD OF RESIST PATTERN FORMATION
Examiner	:	Connie P. Johnson
Art Unit	:	1795

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

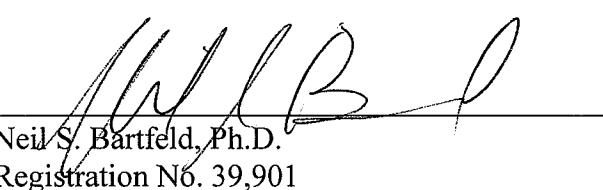
Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing 3 (three) references to be considered by the Examiner.

This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required. If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 7/28/09

By: 

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